

homogenizing an energy distribution of the laser beam emitted from the laser oscillator by a beam homogenizer;

forming a desired pattern by driving and controlling a liquid crystal mask in which the maximum length of each pixel is 50 to 2,000 μm and irradiating the liquid crystal mask with the laser beam homogenized by the beam homogenizer;

setting the energy density on a surface to be marked, of a split laser beam which passed through the liquid crystal mask to 1.0 to 15.0 J/cm^2 ; and

condensing the laser beam for each dot by a lens unit, which passed through the liquid crystal mask, so that the maximum length of each dot is set to 1.0 to 15.0 μm and imaging each dot onto the surface of the article to be marked.

Please add claims 7-10.

7. A microdot mark shape according to claim 1, wherein the height of the protrusion is 0.01 to 5.0 μm .
8. A microdot mark shape according to claim 1, wherein a periphery of the protrusion of said dot mark is recessed.
9. A microdot mark shape according to claim 1 wherein the surface of the article to be marked is a front or a rear surface of an integrated circuit.
10. A microdot shape according to claim 1, wherein said dot mark is formed for product management or various securities.